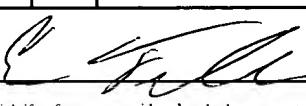


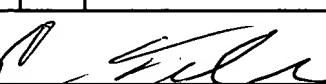
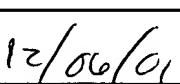
Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-1724		SERIAL NO. Unknown	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Cem Basceri et al.			
					FILING DATE Filed Herewith		GROUP Unknown	
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate
EF	AA			Cem Basceri et al. (as filed)				Filed Concurrently
EF	AB	09/476,516		Cem Basceri (as filed and as amended)				01/03/00
EF	AC	09/580,733		Cem Basceri (as filed)				05/26/00
EF	AD	5,459,635	10/17/95	Tomozawa et al.		361	321.5	
EF	AE	5,618,761	04/08/97	Eguchi et al.		438	785	
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FOREIGN PATENT DOCUMENTS								
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
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EXAMINER				DATE CONSIDERED				
				12/04/01				

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Form PTO-5449 17051 AUG 29 2001 U.S. PATENT & TRADEMARK OFFICE					U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1724	SERIAL NO. 09/005,286	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Cem Basceri et al.				
					FILING DATE July 13, 2001		GROUP Unknown		
U.S. PATENT DOCUMENTS									
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
EF	AA	5,256,455	10/26/93	Numasawa					
EF	AB	5,731,948	01/21/97	Endo					
EF	AC	5,776,254	03/24/98	Yializis et al.					
EF	AD	5,783,253	07/07/98	Yuuki et al.					
EF	AE	5,798,903	07/21/98	Roh					
EF	AF	6,043,526	08/25/98	Dhote et al.					
EF	AG	6,046,345	03/28/00	Ochiai					
EF	AH	6,078,492	04/04/00	Kadokura et al.					
EF	AI	6,153,898	06/20/00	Huang et al.					
EF	AJ	6,037,205	11/28/00	Watanabe					
EF	AK	6,037,205	03/14/00	Huh et al.					
FOREIGN PATENT DOCUMENTS									
		Document Number	Date	Country		Class	Subclass	Translation	
EF	AL	0 855 735 A2	26.01.98	EPO - Zhao et al.; Applied Materials, Inc.				Yes	No
EF	AM	0 957 522 A2	12.05.99	EPO - Ueda, Michihito; Matsushita Electric Ind. Co.,					
EF	AN	WO 98/39497	20.02.98	WIPO - Simpson, John et al.					
EF	AO	0 474 140 A1	30.08.91	EPO - Kamiyama, Satoshi c/o NEC Corporation					
EF	AP	WO 99/64645	11.06.99	WIPO - Narwankar et al.; Applied Materials, Inc;					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
EF	AR	Steve Bilodeau et al., <i>Composition Dependence of the Dielectric Properties of MOCVD Ba_xSr_{1-x}TiO₃</i> , pp. 1-21 (MRS Fall Meeting 12/01/94).							
EF	AS	Steve M. Bilodeau et al., <i>MOCVD BST for High Density DRAM Applications</i> (Preprint for SEMICON/WEST 07/12/95), 2 pages.							
EF	AT	Y-C Choi et al., Abstract, <i>Improvements of the Properties of Chemical-Vapor-Deposited (Ba_xSr_{1-x})TiO₃ Films Through Use of a Seed Layer</i> , 36 JPN. J. APPL. PHYS. Pt. 1, No. 11, pp. 6824-6828 (1997)							
EXAMINER <i>EF</i>			DATE CONSIDERED <i>12/06/01</i>						
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.									

Form PTO-1440 PATENT & TRADEMARK OFFICE AUG 29 2001 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1724		SERIAL NO. 09/905,286		
				APPLICANT Cem Basceri et al.				
				FILING DATE July 13, 2001		GROUP Unknown		
U.S. PATENT DOCUMENTS								
*Examiner Initial	Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
EF	AA 5/470,398	11/28/95	Shibuya et al.					
EF	AB 5/254,505	10/19/93	Kamiyama					
EF	AC 6,156,638	12/05/00	Agarwal et al.					
EF	AD 6,165,834	12/26/00	Agarwal et al.					
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FOREIGN PATENT DOCUMENTS								
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
EF	AR	Chung Ming Chu et al., Abstract, <i>Electrical properties and crystal structure of (Ba,Sr)TiO₃ films prepared at low temperatures on a LaNiO₃ electrode by radio-frequency magnetron ...</i> , 70 APPLIED PHYSICS LETTERS No. 2, pp. 249-251 (1997).						
EF	AS	Kazuhiro Eguchi et al., Abstract, <i>Chemical vapor deposition of (Ba,Sr)TiO₃ thin films for application in gigabit scale dynamic random access memories</i> , 14 INTEGRATED FERROELECTRICS Nos. 1-4, Pt. 1, pp. 33-42 (1997).						
EF	AT	Q.X. Jia et al., Abstract, <i>Structural and dielectric properties of Ba_{0.3}Sr_{0.7} thin films with an epi-RuO₂ bottom electrode</i> , 19 INTEGRATED FERROELECTRICS Nos. 1-4, pp. 111-119 (1998).						
EXAMINER 		DATE CONSIDERED 12/06/01						

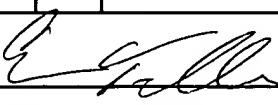
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-1449 O I P E L67 AUG 29 2001 SEARCHED MAILED				U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1724	SERIAL NO. 09/905,286	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Cem Basceri et al.				
				FILING DATE July 13, 2001	GROUP Unknown			
U.S. PATENT DOCUMENTS								
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
EF	AR		Takaaki Kawahara et al., <i>(Ba, Sr)TiO₃ Films Prepared by Liquid Source Chemical Vapor Deposition on Ru Electrodes</i> , 35 JPN. J.					
			APPL. PHYS. Pt. 1, No. 9B, pp. 4880, 4883 (1996).					
EF	AS		<i>Rajesh Khamankar et al., A Novel Low-Temperature Process for High Dielectric Constant BST Thin Films for ULSI DRAM Applications</i> , Microelectronics Research Center, Univ. of Texas at Austin, TX (Undated), 2 pages.					
EF	AT		<i>Yong Tae Kim et al., Abstract, Advantages of RuO_x bottom electrode in the dielectric and leakage characteristics of (Ba,Sr)TiO₃ capacitor</i> , 35 JPN. J. APPL. PHYS. Pt. 1, No. 12A, pp. 6153-6156 (1996).					
EXAMINER			DATE CONSIDERED					
								
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Form PTO-440 OIPE LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) AUG 29 2001 <i>PATENT SEARCHED</i> <i>MAILED 8/29/01</i>		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1724	SERIAL NO. 09/905,286			
		APPLICANT Cem Basceri et al.		FILING DATE July 13, 2001	GROUP Unknown			
U.S. PATENT DOCUMENTS								
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EF	AR	S.H. Paek et al., Abstract, <i>Characterization of MIS capacitor of BST thin films deposited on Si by RF magnetron sputtering</i> , Ferroelectric Thin Films V. Symposium, San Francisco, CA, pp. 33-38 (April 7, 1995).						
EF	AS	N. Takeuchi et al., Abstract, <i>Effect of firing atmosphere on the cubic-hexagonal transition in Ba_{0.99}Sr_{0.01}TiO₃</i> , 98 NIPPON SERAMIKKUSU KYOKAI GAKUJUTSU RONBUNSHI No. 8, pp. 836-839 (1990).						
EF	AT	H. Yamaguchi, et al., Abstract, <i>Reactive coevaporation synthesis and characterization of SrTiO₃-BaTiO₃ thin films</i> , IEEE International Symposium on Applications of Ferroelectrics, Greenville, SC, pp. 285-288 (August 2, 1992).						
EXAMINER <i>En. Teller</i>			DATE CONSIDERED <i>12/06/01</i>					

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-149 149 AUG 29 2001 PATENT & TRADEMARK OFFICE				U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1724	SERIAL NO. 09/905,286	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Cem Basceri et al.				
				FILING DATE July 13, 2001		GROUP Unknown		
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
EF	AR	S. Yamamichi et al., Abstract, <i>Ba + Sr/Ti ratio dependence of the dielectric properties for (Ba_{0.5})Sr_{0.5}TiO₃ thin films prepared by ion beam sputtering</i> , 64 APPLIED PHYSICS LETTERS No. 13, pp. 1644-1646 (1994).						
EF	AS	M. Yamamuka et al., Abstract, <i>Thermal-Desorption Spectroscopy of (Ba,Sr)TiO₃ Thin-Films Prepared by Chemical-Vapor-Deposition</i> , 35 JPN. J. OF APPL. PHYS. Pt. 1, No. 2A, pp. 729-735 (1996).						
EF	AT	Arai T., et al.: <i>Preparation of SrTiO₃ Films on 8-Inch Wafers by Chemical Vapor Deposition</i> , Jap. Journal of Applied Physics, Vol. 35, No. 9B, Part 01, 09/01/96, Pgs. 4875-4879						
EXAMINER <i>EF</i>			DATE CONSIDERED <i>12/06/01</i>					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Form PTO-149 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) AUG 29 2001		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1724	SERIAL NO. 09/905,286		
		APPLICANT Cem Basceri et al.					
		FILING DATE July 13, 2001		GROUP Unknown			
		U.S. PATENT DOCUMENTS					
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
EF	AR		Kim, et al.: <i>Structural and Electrical Properties of BaTiO₃ grown on p-InP (100) by low-pressure metalorganic chemical vapor deposition at</i>				
			<i>low temperature</i> , Applied Physics Letters, US, American Institute of Physics Vol. 65, No. 15, 10/10/94, Pgs. 1955-1957.				
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EXAMINER 		DATE CONSIDERED <i>12/06/01</i>					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							